

# PATENT ABSTRACTS OF JAPAN

(11)Publication number : 2002-061822

(43)Date of publication of application : 28.02.2002

(51)Int.Cl.

F23G 7/06

B01D 53/34

B01D 53/44

B01D 53/74

(21)Application number : 2000-247496

(71)Applicant : CHUGAI RO CO LTD

(22)Date of filing : 17.08.2000

(72)Inventor : YAMAGUCHI HIDEO

TANAKA YUZO

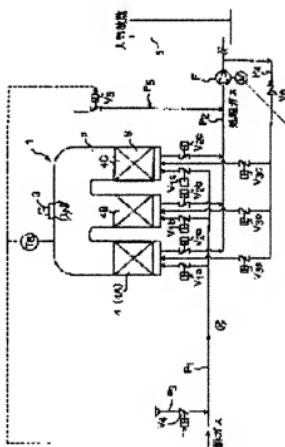
## (54) METHOD FOR TREATING EXHAUST GAS BY HEAT-STORAGE EXHAUST-GAS TREATING EQUIPMENT

### (57)Abstract:

**PROBLEM TO BE SOLVED:** To provide a method for preventing a heat-storage body from being clogged with silica and/or crystallized silicon in a treatment of an organic silicon and an exhaust gas containing a hazardous component by heat-storage exhaust-gas treating equipment.

**SOLUTION:** This exhaust-gas treatment equipment is provided with at least two heat-storage chambers 4 having heat-storage bodies S. One end of each chamber is allowed to communicate with a combustion chamber 2 provided with a heating means 3, and the other end thereof is allowed to communicate with an exhaust gas-supply duct P1 and a treated-gas exhaust duct P2 respectively through open/close valve V1a-V3c.

The supply of exhaust gas containing organic silicon and a hazardous component and the exhaust of treated gas, in which the hazardous gas has been thermally decomposed in the combustion chamber, are switched in succession in each heat-storage chamber by operating the open/close valve. In this case, atmospheric temperature of the combustion chamber is maintained in the range of 750-810°C.



---

**LEGAL STATUS**

[Date of request for examination]

[Date of sending the examiner's decision of rejection]

[Kind of final disposal of application other than the examiner's decision of rejection or application converted registration]

[Date of final disposal for application]

[Patent number]

[Date of registration]

[Number of appeal against examiner's decision of rejection]

[Date of requesting appeal against examiner's decision of rejection]

[Date of extinction of right]